

# Semiconducting Behavior of Type-I Si Clathrate $K_8Ga_8Si_{38}$

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## Supplementary Material

Table S1. Experimental and refined details for the single-crystal measurements. S2

Table S2. Atomic positions and displacement parameters of  $K_8Ga_{16}Si_{38}$ . S4

S1. Experimental and refined details for the single-crystal measurements.

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Crystal data	
Chemical Formula (Structural analysis)	K <sub>8</sub> Ga <sub>8.3(1)</sub> Si <sub>37.7</sub>
M <sub>r</sub>	1950.283
Crystal color	Gray, Metallic luster
Crystal size (mm)	0.20 x 0.15 x 0.04
Temperature (K)	293
Space group	Pm <sup>-</sup> 3n (No. 223)
A (Å)	10.4261(2)
V (Å <sup>3</sup> )	1133.35(4)
Z	1
D <sub>x</sub> (g/cm <sup>3</sup> )	2.858
μ(MoKα) (cm <sup>-1</sup> )	6.580
Data Collection	
Radiation	MoKα ( $\lambda = 0.71073 \text{ \AA}$ )
Diffractometer	Bruker SMART APEX CCD
Data collection method	$\omega$ scans
Absorption correction	Empirical SADABS in SAINT-Plus-NT
T <sub>min</sub> , T <sub>max</sub>	0.3612, 0.5276
2θ <sub>max</sub> (°)	61.04
No. of measured, independent and observed reflections	8352, 338, 321
R <sub>int</sub>	3.15
Refinement	
No. of parameters	19
Refinement on	F <sup>2</sup>
$R[F^2 > 2\sigma(F^2)]$ , wR(F <sup>2</sup> ), S	1.30, 3.27, 1.098
Weighting scheme	w = 1/[σ <sup>2</sup> (F <sub>O</sub> <sup>2</sup> ) + (0.0381P) <sup>2</sup> ], where P = (F <sub>O</sub> <sup>2</sup> +2F <sub>C</sub> <sup>2</sup> )/3
(Δ/σ) <sub>max</sub>	0.001
Δρ <sub>max</sub> , Δρ <sub>min</sub> (eÅ <sup>-3</sup> )	0.27, -0.30

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Programs

Data collection: SMART-NT (Bruker, 1999) [S1.1]; cell refinement: SAINT-Plus-NT (Bruker, 1999) [S1.2]; data reduction: SAINT-Plus-NT (Bruker, 1999) [S1.2]; program used to refine structure: SHELXL-97 (Sheldrick, 1997) [S1.3].

## References

- [S1.1] Bruker (1999). SMART-NT. Version 5.625. Bruker AXS Inc., Madison, Wisconsin, USA.
- [S1.2] Bruker (1999). SAINT-plus-NT. Version 6.45. Bruker AXS Inc., Madison, Wisconsin, USA.
- [S1.3] G.M. Sheldrick, A short history of SHELX, *Acta Cryst. A* **64** (2008) 112-122.

S.2 Atomic positions and displacement parameters of  $K_8Ga_{16}Si_{38}$ .

Atom	Multiplicity					
	Wyckoff	x	y	z	Occ.	$U_{eq}$
Letter						
K1	2a	0	0	0	1	0.0127(2)
K2	6d	1/4	1/2	0	1	0.0266(2)
E1	6c	1/4	0	1/2	0.607(5) Ga 0.393 Si	0.0097(1)
E2	16i	0.18442(2)	x	x	0.026(2) Ga 0.974 Si	0.0088(2)
E3	24k	0	0.30577(2)	0.11804(3)	0.179(2) Ga 0.821 Si	0.0095(1)

  

Atom	$U_{11}$	$U_{22}$	$U_{33}$	$U_{12}$	$U_{13}$	$U_{23}$
K1	0.0127(2)	$U_{11}$	$U_{11}$	0	0	0
K2	0.0179(3)	0.0310(3)	$U_{22}$	0	0	0
E1	0.0107(2)	0.0092(2)	$U_{22}$	0	0	0
E2	0.0088(2)	$U_{11}$	$U_{11}$	-0.00051(8)	$U_{12}$	$U_{12}$
E3	0.0092(2)	0.0098(2)	0.0096(2)	0	0	-0.00018(9)